REMARKS

The Applicants thank the Examiner for the thorough consideration given the present application. Claims 1-14 are pending. Claims 1 and 15 are independent. By this Amendment, claim 1 is amended and claim 15 is added. No new matter is involved.

The Examiner is respectfully requested to reconsider the rejections in view of the amendments, and the remarks set forth herein.

Examiner Interview

Applicants acknowledge with appreciation the courtesies extended by Examiner Vargot to their representative, Mr. Robert J. Webster, Reg. No. 46,472, during the telephone interviews conducted on May 25, 2010 and June 8, 2010. During those interviews, agreement was not reached concerning whether the existing claims patentably define over the applied art, and claim amendment language was discussed in an attempt to reach agreement on claims that would patentably define over the applied art. Although agreement was not reached concerning whether the proposed amendments to the claims would patentably define over the applied art, Examiner Vargot indicated that the proposed language did appear reasonable and recommended that such amendments be filed for his consideration on their merits.

Rejections Under 35 U.S.C. §103(a)

Claims 1-14 stand rejected under 35 U.S.C. §103(a) as being unpatentable over U.S. Patent 6,091,537 to Sun et al. (Sun"). This rejection is respectfully traversed.

Art Unit: 1791 Reply to Office Action of March 4, 2010

Claim 1 recites a method of producing a compact movable structure for a light shaping unit

comprising: forming a light shaping unit by from a layer of non-photoresist material provided on a

carrier of another material; and subsequently forming, from said carrier layer, an intermediate

micromechanical plate for movably supporting the light shaping unit in a micromechanical structure

Sun does not disclose, suggest, or otherwise render obvious the claimed invention. In

all of Sun's embodiments, Sun makes its light shaping unit from a photoresist material.

However, claim 1 recites that the light shaping unit is made from a non-photoresist material.

Applicants make their lens from a polymer such as, for example, CYTOP or Parylene – see

page 3, last full paragraph of applicants' specification.

Additionally, Sun discloses, in col. 3, lines discloses, in col. 3, lines 22-33, that the

photoresist microlens is formed over region 13 after microlens stage support portion made of

SiO2 layer 74 is etched.

Thus, Sun teaches away from the claimed method.

Therefore, independent claim 1 is in condition for allowance.

All dependent claims are in condition for allowance, also due to their dependency from

allowable independent claims, or due to the additional novel features set forth therein.

Accordingly, reconsideration and withdrawal of the rejection of claims 1-14 under 35

U.S.C. §103(a) are respectfully requested.

Claim 15, has been added. Claim 15 recites a method of producing a compact movable

structure for a light shaping unit comprising: forming a light shaping unit from a material provided

on a carrier of another material; and subsequently forming, an intermediate micromechanical plate

from said carrier as part of a micromechanical structure for movably supporting the light shaping

unit, wherein the intermediate micromechanical plate directly supports the light shaping unit.

Claim 15 patentably defines over Sun because, for example, Sun does not disclose,

suggest, or otherwise render obvious, subsequently forming, an intermediate micromechanical

plate from said carrier as part of a micromechanical structure for movably supporting the light

shaping unit, wherein the intermediate micromechanical plate directly supports the light shaping

unit, as claimed. As pointed out above, Sun discloses, in col. 3, lines discloses, in col. 3, lines

22-33, that the photoresist microlens is formed over region 13 after microlens stage support

portion made of SiO2 layer 74 is etched.

Accordingly, consideration and allowance of claim 15 are respectfully requested.

CONCLUSION

Since the remaining patents cited by the Examiner have not been utilized to reject claims,

but merely to show the state of the art, no comment need be made with respect thereto.

All of the stated grounds of rejection have been properly traversed, accommodated, or

rendered moot. It is believed that a full and complete response has been made to the outstanding

Office Action, and that the present application is in condition for allowance.

If the Examiner believes, for any reason, that personal communication will expedite prosecution of this application, he is invited to telephone Robert J. Webster (Reg. No. 46,472) at (703) 208-4076(direct line).

If necessary, the Commissioner is hereby authorized in this, concurrent, and future replies to charge payment or credit any overpayment to Deposit Account No. 02-2448 for any additional fees required under 37 C.F.R. §§1.16 or 1.17, particularly extension of time fees.

Date: _____ JUN **2 1** 2010

Respectfully submitted,

Paul C. Lewis

Reg. No. 43,368

BIRCH, STEWART, KOLASCH & BIRCH, LLP

8110 Gatehouse Road, Suite 100E

P. O. Box 747

Falls Church, VA 22040-0747

(703) 205-8000

PCL/RJW:la